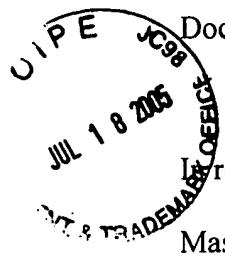


JFW



Docket No.: 052775-0024

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of : Customer Number: 20277
Masahiro NAKAYAMA, et al. : Confirmation Number: 1716
Application No.: 10/662,524 : Group Art Unit: 2826
Filed: September 16, 2003 : Examiner: QUINTO, KEVIN V

For: CHAMFERED FREESTANDING NITRIDE SEMICONDUCTOR WAFER AND
METHOD OF CHAMFERING NITRIDE SEMICONDUCTOR WAFER

INFORMATION DISCLOSURE STATEMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached form PTO-1449. It is respectfully requested that the references be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Each non-English language reference was first cited in a corresponding foreign application office action and its relevance discussed therein. A copy of the foreign office action, is attached for the Examiner's information.

Please charge any shortage in fees due in connection with the filing of this paper,
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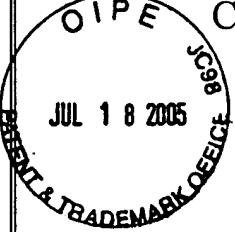
Respectfully submitted,

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Date: July 18, 2005

**Please recognize our Customer No. 20277
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INFORMATION DISCLOSURE CITATION IN AN APPLICATION  (PTO-1449)				ATTY. DOCKET NO. 052775-0024	SERIAL NO. 10/662,524	
				APPLICANT Masahiro NAKAYAMA, et al.		
				FILING DATE September 16, 2003	GROUP 2826	
U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Code ₂ (<i>if known</i>)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
	US					
	US					
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FOREIGN PATENT DOCUMENTS						
EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Codes-Number &-Kind Codes (<i>if known</i>)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation Yes No
		JP 03-001535	01/08/1991	ASAHI GLASS CO LTD.		JAPAN (w/English Abstract)
		JP 03-280537	12/11/1991	SHIN ETSU HANDOTAI CO LTD.		JAPAN (w/English Abstract)
		JP 2002-208572 A	07/26/2002	EBARA CORP.		JAPAN (w/English Abstract)
		JP 09-109010	04/28/1997	SHIN ETSU HANDOTAI CO LTD.		JAPAN (w/English Abstract)
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)						
EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.				
EXAMINER				DATE CONSIDERED		

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Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.